UNITED STATES PATENT AND TRADEMARK OFFICE

BIB DATA SHEET

CONFIRMATION NO. 6791

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** CONTINUING DATA ***************************
   This application is a 371 of PCT/JP03/08097 06/26/2003

** FOREIGN APPLICATIONS ************************
   JAPAN 2002-187566 06/27/2002
   JAPAN 2003-084774 03/26/2003

** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **
   09/14/2006

Foreign Priority claimed ☑ Yes ☐ No			STATE OR COUNTRY	SHEETS DRAWINGS	TOTAL CLAIMS	INDEPENDENT CLAIMS
35 USC 119(a-d) conditions met ☑ Yes ☐ No	☐ Met after Allowance					
Verified and Acknowledged	/SONYA D MCCALL SHEPARD/ Examiner's Signature	Initials	JAPAN	12	18	6

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TITLE

Substrate treating apparatus and method for manufacturing semiconductor device

FILING FEE RECEIVED 1630	FEES: Authority has been given in Paper No._____ to charge/credit DEPOSIT ACCOUNT No._____ for following:	☐ All Fees
		☐ 1.16 Fees (Filing)
		☐ 1.17 Fees (Processing Ext. of time)
		☐ 1.18 Fees (Issue)
		☐ Other _____
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